

## **AMENDMENTS TO THE CLAIMS**

The following listing of claims will replace all prior versions and listings of claims in the application.

### **LISTING OF CLAIMS**

1. – 4. (Cancelled).

5. (Currently Amended) A mask vapor deposition device comprising:

a deposition mask including silicon and being provided with an electrode arranged interdigitally in a mask pattern portion, the mask having a wiring connected to the electrode to supply a charge to a mask pattern section, the deposition mask having an electrostatic chucking mechanism for attracting a subject for deposition using electrostatic attraction generated in the mask pattern section and controlling a depositing of deposition material on the deposition subject with a predetermined pattern;

an evaporation source for evaporating the deposition material; and

a unit for supplying the charge to the mask pattern section;

wherein at least the deposition mask and the evaporation source are placed in a vacuum chamber.

6. – 12. (Cancelled).

13. (Currently Amended) An apparatus for manufacturing a display panel so that an organic compound, which is used for forming electroluminescent elements, is deposited on a glass substrate with a predetermined pattern, the apparatus comprising:

a deposition mask including silicon and being provided with an electrode arranged interdigitally in a mask pattern portion, the mask having a wiring connected to the electrode to supply a charge to a mask pattern section, the deposition mask having

an electrostatic chucking mechanism for attracting a subject for deposition using electrostatic attraction generated in the mask pattern section and controlling a depositing of a deposition material on the deposition subject with a predetermined pattern;

an evaporation source for evaporating the organic compound; and

a unit for supplying the charge to the mask pattern section;

wherein at least the mask and the source are placed in a vacuum chamber.

14. – 15. (Cancelled).